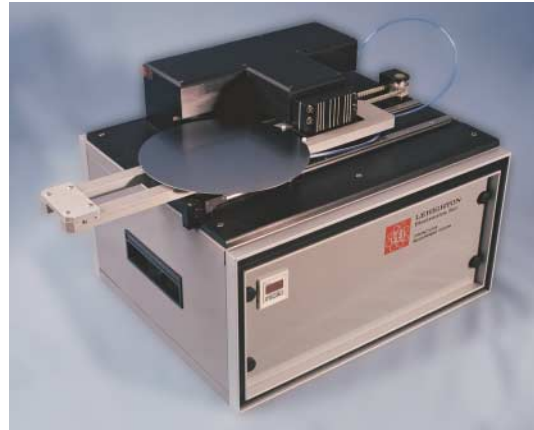


Models/Options




1510 standalone

LEI 1510RP The unit shown accommodates 2" to 200mm(8") cassettes (max. diameter).

	1510B			1510C		
	manual	RP	RS	manual	RP	RS
throughput (wafer test time)						
<i>single wafer</i>						
9 point plan	0:45	0:45	0:45	0:22	0:22	0:22
24 point plan	2:45	2:45	2:45	1:15	1:15	1:15
55 point plan	5:30	5:30	5:30	2:30	2:30	2:30
<i>25 wafer cassette*</i>						
10 center plan	N/A	27:00	27:00	N/A	13:50	13:50
24 point plan	N/A	42:15	42:15	N/A	21:15	21:15
55 point plan	N/A	80:00	80:00	N/A	41:00	41:00
robotic handling of sample wafers						
<i>single cassette</i>	NO	YES	YES	NO	YES	YES
<i>multiple cassette</i>	NO	NO	YES	NO	NO	NO
repeatability						
<i>positional</i>	±.003" (.0762mm)			±.0015" (.0381mm)		
<i>rotational</i>	±2.5°			±1°		

* Ideal throughput does not include time to change cassette.
Throughput times are calculated with the Auto Reference feature on.
RP(Robotic Pick-and-Place), RS(Robotic Sort)


Models/options